



AF/ 2822
PATENT
5310-03000

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/744,877
Confirmation No.: 8711
Filing Date: January 29, 2001
Inventor(s):

Halimaoui et al.

Title: PROCESS FOR FORMING
AN OXIDE LAYER OF NON-
UNIFORM THICKNESS ON
THE SURFACE OF A
SILICON SUBSTRATE

§ Examiner: Novacek, Christy L.
§ Group/Art Unit: 2822
§ Atty. Dkt. No: 5310-03000
§
§
§
§
§
§
§
§
§
§

<p>CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8</p> <p>DATE OF DEPOSIT: <u>11.21.03</u></p> <p>I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail on the date indicated above and is addressed to:</p> <p>Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450</p> <p><i>Gail Ballard</i> Gail Ballard</p>

AMENDMENT; RESPONSE TO FINAL OFFICE ACTION MAILED AUGUST 21, 2003

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the final Office Action mailed August 21, 2003 (Paper No. 15), please
amend the above-specified application as follows:

Amendments to the claims are reflected in the listing of claims that begin on page 2 of this
paper.

Remarks/Arguments begin on page 4 of this paper.

RECEIVED
DEC - 3 2003
TECHNOLOGY CENTER 2822